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April 19, 2007

**AMENDMENT AFTER  
ALLOWANCE**

BY FACSIMILE ONLY

Atty Docket No. :	JCLA7109-R
Appl. No. :	10/603,924
Filing Date :	June, 24, 2003
Pages :	Cover + 12

Fax No. :	571-273-8300
Attention :	EXAMINER: NGUYEN, THANH T.
Group Unit :	2813
From :	Jewei Huang, Reg. No. 43,330
MESSAGE :	Enclosed herewith is a Amendment After Allowance with amended drawings in 12 pages.

Sir:

I hereby certify that this correspondence is being facsimile transmitted to the Patent and Trademark Office on April 19, 2007 at the above indicated fax number.

Sign:   
Michelle Chang

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Application No.: 10/603,924

Docket No.: JCLAT109-R

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

THANH T.	Hu et al.	Examiner : NGUYEN,
Serial No. : 10/603,924		Art Unit : 2813
Filed : June 24, 2003		Docket No. : JCLAT109-R
For : METHOD OF REMOVING CONTAMINANTS FROM A SILICON WAFER AFTER CHEMICAL-MECHANICAL POLISHING OPERATION		

AMENDMENTS AFTER ALLOWANCE UNDER 37 CFR 1.312

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir,

The Notice of Allowance dated January 24, 2007 has been carefully considered. In response thereto, please enter the following amendments and consider the remarks hereinafter.